

Notice of References Cited

Application/Control No.

09/597,161

Applicant(s)/Patent Under
Reexamination
OKABE ET AL.

Examiner

José R Díaz

Art Unit

2815

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Okada et al. , "Furnace grown Gate Oxynitride Using Nitric Oxide (NO)", IEEE Transactions on Electron Devices, Volume: 41 Issue: 9 , Sept. 1994, Page(s): 1608 -1613
	V	
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